

NOV 18 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
(Attorney Docket No. 100191)

Applicant: Schroeder et al.

Application No. 10/660,379

Filed: September 11, 2003

For: CHEMICAL-MECHANICAL  
POLISHING COMPOSITION  
AND METHOD FOR USING  
THE SAMEExaminer: George A. Goudreau  
Art Unit: 1763Certificate of Facsimile Transmission

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(Sender's signature)RESPONSE TO OFFICE ACTION

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

In response to the Office Action dated August 18, 2004, please consider the following remarks.

REMARKS*The Pending Claims*

The pending claims are directed to a chemical-mechanical polishing composition comprising fumed silica particles, at least one alkaline earth metal, an oxidizing agent, and a liquid carrier, as well as methods of polishing a substrate using the same. Claims 1-86 currently are pending.

*Summary of the Office Action*

The Office Action rejects claims 1-86 under 35 U.S.C. § 112, second paragraph, as allegedly indefinite for failing to particularly point out and distinctly claim the subject matter which applicants regard as their invention. The Office Action further rejects claims 1-6, 11,

Cabot Microelectronics Corporation  
870 North Commons Drive  
Aurora, Illinois, 60504  
United States of America  
Tel. (630) 375-5465